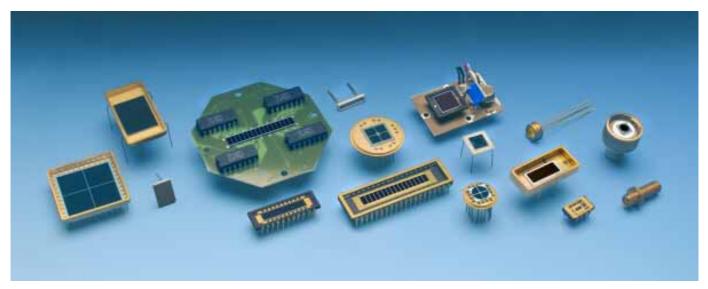


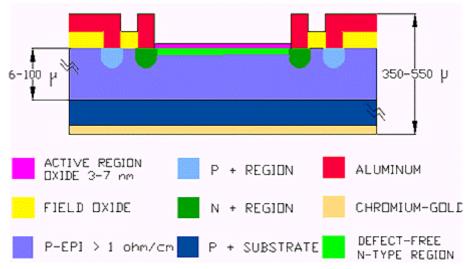
真空紫外・軟×線シリコンフォトダイオード



Absolute XUV Silicon Photodiodes

Silicon p-n junction photodiodes (AXUV-series) have been developed by International Radiation Detectors for applications in the vacuum ultraviolet, extreme ultraviolet and the soft x-ray (XUV,wavelength range 1800 Å to 2 Å, energy range 7 eV to 6000 eV) spectral region. Unlike common p-n junction diodes, these diodes do not have a doped dead-region and have zero surface recombination resulting in near theoretical quantum efficiencies for XUV photons and other low energy particles. The AXUV diodes are internal photoelectric devices and hence are less sensitive to minute vacuum system contaminants than conventional XUV detectors based on the external photoelectric effect.

These diodes are fabricated by an ULSI (Ultra Large Scale Integrated Circuit) compatible process and their construction is shown in the following figure.



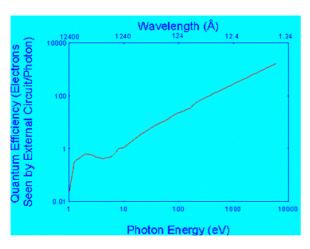
Developed in collaboration with NIST, NOAA, NIH, LLNL, NCAR and LANL



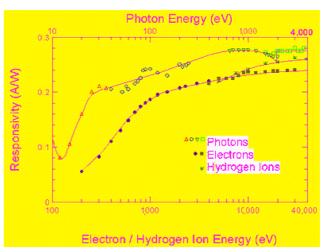
仁 木 工 芸 株式会社 NIKI GLASS CO., LTD.

〒108-0073 東京都港区三田 3-9-7 ニキグラスビル TEL: 03-3456-4700 FAX: 03-3456-3423 〒532-0011 大阪市淀川区西中島 6-2-16 TEL: 06-4805-4155 FAX: 06-4805-0211

URL http://:www.nikiglass.co.jp



Typical quantum efficiency of the AXUV photodiodes.



Typical responsivity of the AXUV photodiodes to photons, electrons and hydrogen ions

Absolute Devices / Transfer Standards

| | Sensitive Area (mm²) | Size (mm) | Package Type | Shunt Resistance (M-Ohm) @ 10 mV | Dark Current @ 50V | Capacitance @ 0V | Risetime (10%-90%) |
|----------------|----------------------------|--------------|-----------------|---|--------------------------|---------------------|-----------------------|
| <u>AXUV100</u> | 100 | 10 X 10 | Ceramic | 100 | * | 20 nF** | 10 μSec** |
| AXUV100EUT ## | 100 | 10 X 10 | Ceramic | 100 | * | 20 nF** | 10 μSec** |
| AXUVSP2 | 96 | 6 X 16 | Ceramic | 100 | * | 20 nF** | 10 μSec** |
| AXUV96 | 96 | 6 X 16 | Metal | 100 | * | 20 nF** | 10 μSec** |
| AXUV50HE1 | 50 | 8Ø | Ceramic | 10 | * | 3 nF** | 6 μSec** |
| AXUV20 | 20 | 5Ø | Metal | 1000 | * | 2 nF** | 2 μSec** |
| AXUV20A | 20 | 5Ø | Ceramic | 100 | * | 5 nF** | 1 μSec** |
| AXUV20BNC | 20 | 5Ø | BNC | 1000 | * | 2 nF** | 2 μSec** |
| AXUV20HE1 | 20 | 5Ø | Ceramic | 10 | * | 500 pF** | 0.2 μSec** |
| AXUV300 # | 330 | 22 X 15 | Plastic | 20 | * | 40 nF** | 15 µSec** |
| AXUV300M/G | 330 | 22 X 15 | Metal | 20 | * | 40 nF** | 15 µSec** |
| <u>AXUV576</u> | 576 | 24 X 24 | Metal | 5 | * | 120 nF** | 50 μSec** |
| AXUV10 | 10 | 10 X 1 | Ceramic | 1000 | * | 2 nF** | 2 μSec** |
| AXUV36@ | 36 | 6 X 6 | Metal | 10 | * | 10 nF** | 10 μSec** |

AXUV-1600 with five AXUV-300 chips is available

AXUV-100 photodiode with eutectically mounted chip for vacuum environments lower than 10^-9 torr @ With 5 micron physical silicon thickness.

All AXUV products have at least 7 orders of magnitude of dynamic range.

Please specify if detectors with larger than dynamic range are required.

^{*} May be selected for a specific application at no additional cost.

^{**} Devices with better values may be selected.